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IN THE UNITED STATES ELECTED OFFICE  
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UNDER THE PATENT COOPERATION TREATY

**PRELIMINARY AMENDMENT**  
**ACCOMPANYING THE FILING OF AN APPLICATION**

APPLICANT(s): Yoko Watanabe et al.  
ATTORNEY DOCKET NO.: 075834.00404  
INTERNATIONAL APPLICATION NO.: PCT/JP03/08176  
INTERNATIONAL FILING DATE: June 27, 2003  
INVENTION: MASK AND INSPECTION METHOD THEREFOR AND  
PRODUCTION METHOD FOR SEMICONDUCTOR  
DEVICE  
CUSTOMER NO.: 33448

Mail Stop PCT  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

**TITLE OF THE INVENTION**

Please amend the title of the invention to:

~~MASK AND INSPECTION METHOD THEREFOR AND PRODUCTION  
METHOD FOR SEMICONDUCTOR DEVICE~~

MASK, METHOD OF INSPECTING THE SAME, AND METHOD OF  
PRODUCING SEMICONDUCTOR DEVICE